

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. SEPP15.001AUS	APPLICATION NO. 10/003,749
	APPLICANT Skarp et al.	
	FILING DATE October 23, 2001	GROUP 1762

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
<i>[Signature]</i>	1	US 2003/0129298 A1	07/10/03	Tera et al.			
<i>[Signature]</i>	2	US 2001/0031379 A1	10/18/01	Tera et al.			
<i>[Signature]</i>	3	US 2002/0003403 A1	01/10/02	Ghosh et al.			
<i>[Signature]</i>	4	US 2001/0052752 A1	12/20/01	Ghosh et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
<i>[Signature]</i>	5	WO 03/008110 A1	01/30/03	PCT			YES	NO

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

EXAMINER INITIAL		
<i>[Signature]</i>	6	Kukli et al, "Atomic layer epitaxy growth of aluminum oxide thin films from a novel Al(CH ₃) ₂ Cl precursor and H ₂ O.", J. Vac. Sci. Technol. A 15(4), July/Aug 1997, pp. 2214-2218
<i>[Signature]</i>	7	Hiltunen et al. "Growth and Characterization of Aluminum Oxide Thin Films Deposited from Various Source Materials by Atomic Layer Epitaxy and Chemical Vapor Deposition Processes", Materials Chemistry and Physics, 28 (1991) pp. 379-388
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EXAMINER <i>[Signature]</i>	DATE CONSIDERED 11/21/03
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